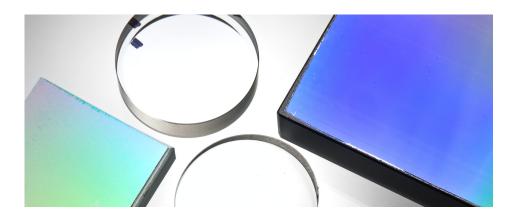


Gaining Deeper Insights into Thin Film Response

Overcoming spectral oscillations using the Agilent Cary universal measurement accessory



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Introduction

A more detailed account of this work was first published in Optics Express 16129, 2 July 2012, Vol. 20, No. 14.1

Designers and manufacturers of high-quality multilayer optical coatings require reliable methods to measure optical constants of thin film materials with a high degree of accuracy. This is normally achieved using UV-visible-IR spectrophotometry to acquire normal and quasi-normal transmittance (T) and reflectance (R) spectra of a sample. Understanding the accuracy of the data produced and the source of any errors (random or systematic) will lead to more reliable sample characterization.^{2,3}

Random errors (random noise) vary from one point to another in the measurement data set, and have been shown to have minimal impact on the characterization results.² However, systematic errors that result in an offset of spectral characteristics as a whole, or cause large-scale wavelength variations of T and R curves, are especially critical for the accurate determination of thin film parameters.²

Valuable information relating to data accuracy is provided by calculating the total losses (TL) of the thin film sample^{4,5} using TL(λ) = 100% – R(λ) – T(λ). Typically, in the spectral range where the substrate and the thin film are nonabsorbing and nonscattering, zero total losses would be expected, whereas with absorbing films, TL(λ) decreases with increasing λ .

When analyzing spectra for TL, researchers often observe oscillations, which may cause doubt about the quality of the data. Sources of such oscillations include:

- The difference in angles of incidence (AOI) at which T and R are measured
- Absorption in a thin film acting in combination with interference effects
- A slight thickness nonuniformity of the film

A full report on the origins of oscillations in TL is discussed in reference 1.1 This application note demonstrates how an Agilent Cary 5000 UV-Vis-NIR spectrophotometer equipped with a universal measurement accessory (UMA) is able to provide previously unreported insights into thin film characterization due to its ability to measure T and R without moving the sample.

Experimental

Samples

A ${\rm Ta_2O_5}$ film of 292 nm thickness was deposited onto a Suprasil substrate of 25 mm diameter and 6.35 mm thickness using a magnetron-sputtering Leybold Optics HELIOS plant.¹ A second, preprepared ${\rm Ta_2O_5}$ sample with a slightly different film thickness was also used. Transmittance data for s-polarized light were measured at 7° and 10°, and s-polarized reflectance data were measured at 10°.

Instrumentation

- Agilent Cary 5000 UV-Vis-NIR spectrophotometer
- Agilent universal measurement accessory

The UMA is a highly automated, variable-angle, absolute specular reflectance and transmittance system. The linearly polarized beam that illuminates the sample can be measured in transmission, and by rotating the detector assembly about

an axis through the sample and perpendicular to the plane of incidence, in reflection, as indicated in Figure 1. Therefore, the same spot on the sample is used for both T and R measurements. This multiple measurement mode capability of the UMA results in more accurate, rapid, and complete optical characterization of thin films. These data could also have been collected on a Cary 7000 universal measurement spectrophotometer (UMS).

Results and discussion

Traditionally, reflectance and transmittance measurements have been performed using spectrophotometers fitted with different accessory attachments. In practice, different areas of the sample surface may be tested. If the deposition process produces a film with a nonuniform thickness, it is reasonable to expect that reflectance and transmittance measurements are affected.

With the development of the UMA, it is now possible to measure T and R at the same sample point, overcoming one source of oscillations on the results. In this study, an Agilent Cary 5000 double beam UV-Vis-NIR spectrophotometer equipped with a UMA was used to acquire transmittance data for s-polarized light at 7° and 10°, and s-polarized reflectance data at 10°. To verify the capabilities of the UMA, the same sample was reanalyzed a few months later using a second UMA unit and different sample mounts.

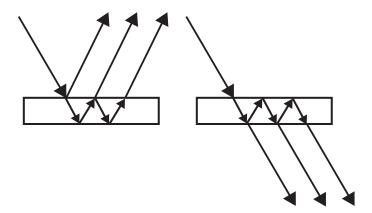


Figure 1. Schematic of the Agilent UMA, an absolute variable-angle reflectance and transmission accessory capable of front and back surface reflection (left) and direct and inter-reflected transmission (right) measurement.

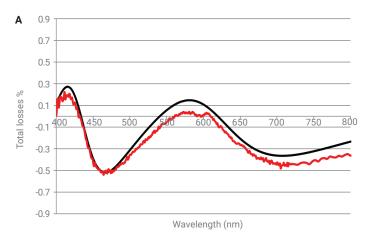
The first experiment considered TL calculated on the basis of T and R measurements taken at different AOI using the first UMA unit according to: $TL^{(s)}(\lambda) = 100\% - T^{(s)}(7^{\circ}, \lambda) - R^{(s)}(10^{\circ}, \lambda)$. The experimental total losses are plotted in Figure 2A (red line). Oscillations of approximately 0.4% magnitude are clearly observed. The solid curve (black line) in Figure 2A presents a theoretical approximation of total losses as expected when T and R are measured at different angles of 7 and 10 degrees, respectively. There is good agreement between the experimental and theoretical results shown in Figure 2A. This agreement confirms that the oscillations are due to only the difference in AOI and that the effect of thickness nonuniformity does not contribute to total losses spectral behavior.

Figure 2B shows experimental total losses, calculated from T and R measurements taken at equal AOI: $TL^{(s)}(\lambda) = 100\% - T^{(s)}(7^{\circ}, \lambda) - R^{(s)}(7^{\circ}, \lambda)$.

The absence of any oscillations is clearly observed. This is further confirmation that thickness nonuniformity does not affect total losses when T and R measurements are acquired at the same point of the sample.

The second experiment acquired T and R data from the original sample on a new sample mount using a different UMA unit coupled to the Cary 5000 spectrophotometer. The solid black curve in Figure 3A represents the data acquired using a UMA unit.

The same sample was re-analyzed using a different UMA unit four months later and the results are represented by the red line. Visually, both data sets are indistinguishable, demonstrating the excellent reproducibility between multiple UMA units. This gives confidence in results obtained from different UMA/UMS systems, for example, within a manufacturing environment where more than one instrument can be used.



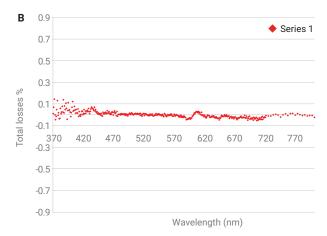


Figure 2. (A) Comparison of $TL^{(s)}(\lambda) = 100\% - T^{(s)}(7^{\circ}, \lambda) - R^{(s)}(10^{\circ}, \lambda)$ calculated from experimental data and $TL^{(s)}AOI(\lambda)$ calculated by theoretical equation.¹ (B) Total losses $TL^{(s)}(\lambda) = 100\% - T^{(s)}(7^{\circ}, \lambda) - R^{(s)}(7^{\circ}, \lambda)$ calculated from experimental data.

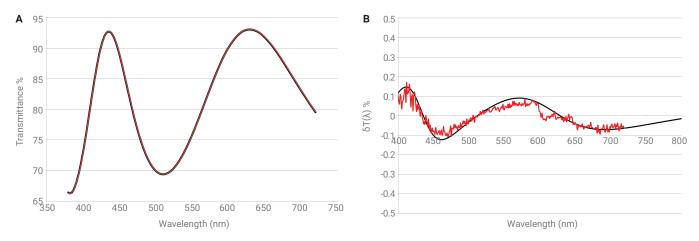


Figure 3. (A) Comparison of two transmittance spectra acquired using two different UMA accessories coupled to an Agilent Cary 5000 spectrophotometer. The data relate to the same Ta_2O_5 sample. (B) Comparison of $T^{(s)}(\lambda) = T^{(s,1)}(7^{\circ}, \lambda) - T^{(s,2)}(7^{\circ}, \lambda)$ calculated from experimental data (red line) and by theoretical equations (black line).

The difference between the two transmittance spectra is indicated by the red line in Figure 3B. Oscillations of approximately 0.15% in magnitude can clearly be observed. The solid curve (black line) in Figure 3B indicates a theoretical approximation of total losses calculated with $\Delta d = -0.3$ nm. This thickness nonuniformity value corresponds to approximately 0.1% of the geometrical film thickness (d = 292 nm). This is in full agreement with the thickness nonuniformity level in the HELIOS deposition plant.

Conclusions

One cause of oscillations in total losses spectra arise from slight thickness nonuniformity of the thin film sample. However, this source of error can be small when compared to variations in AOI between T and R measurements. AOI errors can be eliminated using an advanced spectrophotometric accessory (developed by Agilent Technologies) fitted to an Agilent Cary 5000 UV-Vis-NIR spectrophotometer. The UMA is a variable-angle specular reflectance and transmittance system that acquires T and R data without moving the sample or the incident beam onto the sample.

The results presented in this report demonstrate that the residual oscillations observed after eliminating AOI variations are minimal and are in full agreement with the theoretical values. The findings confirm that the effect of thickness nonuniformity does not contribute to total losses spectral behavior when an instrument capable of T and R measurement at the same point of the investigated sample is used. The latest in multiangle spectral photometry provides researchers with more accurate spectroscopic information for the characterization of thin films than has been available previously.

References

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